AUTOMOTIVE SEMICONDUCTOR FOR PURCHASING / BUYER

JOHN COTNER SECURITY ARCHITECT - AUTOMOTIVE

AMF-AUT-T2693 | JUNE 2017



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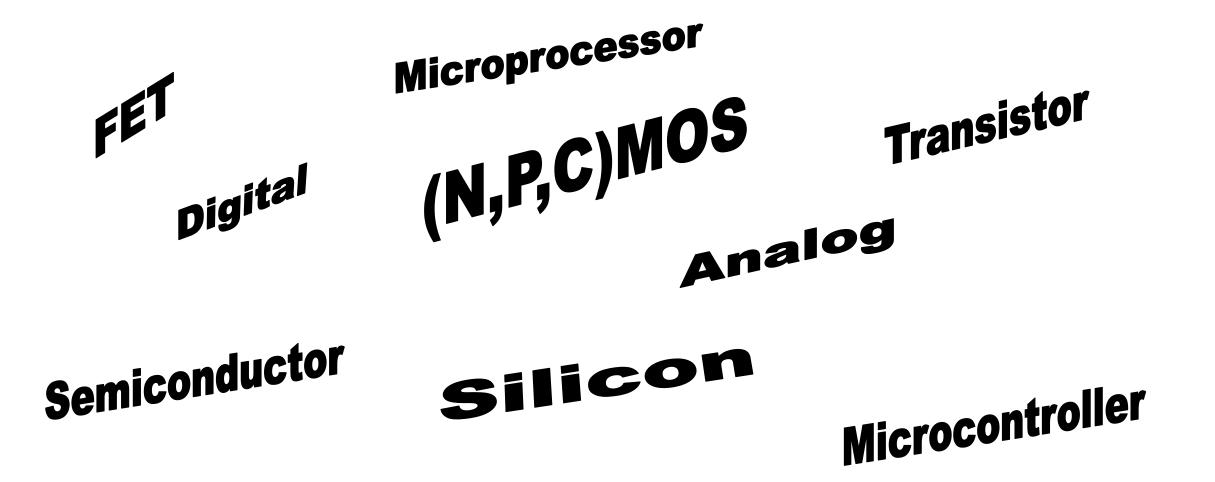
AGENDA

- Introduction to Integrated Circuits (IC's)
- IC Manufacturing Process
- Tooling, Equipment, and Investment Needs for IC Design and Manufacture
- Semiconductor Manufacturing Video

INTRODUCTION TO INTEGRATED CIRCUITS (ICS)



Semiconductor Terms and Acronyms





What is a Semiconductor?



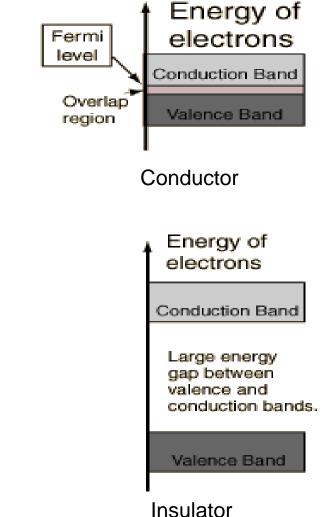


• A conductor carries electricity like a pipe carries water.

 A semiconductor controls the flow of electricity like a faucet controls water.



 An insulator stops the flow of electricity like a plug blocks water.





Semiconductor Basics

- Copper, a conductor, has one electron per atom available for conduction
- A useful semiconductor requires about 10 orders of magnitude less
- This means adding as little as one doping atom in a billion
- Impurities have to be below one in 10 billion

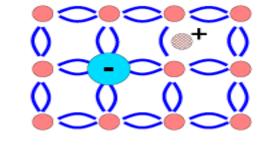
E



n Type doped with P or As

E

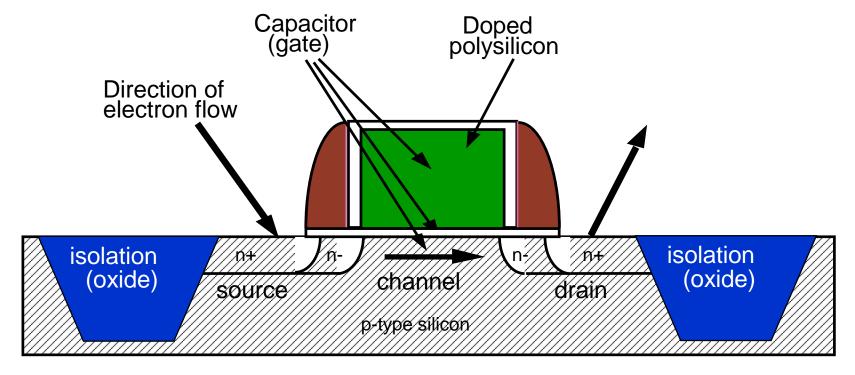
p Type doped with B





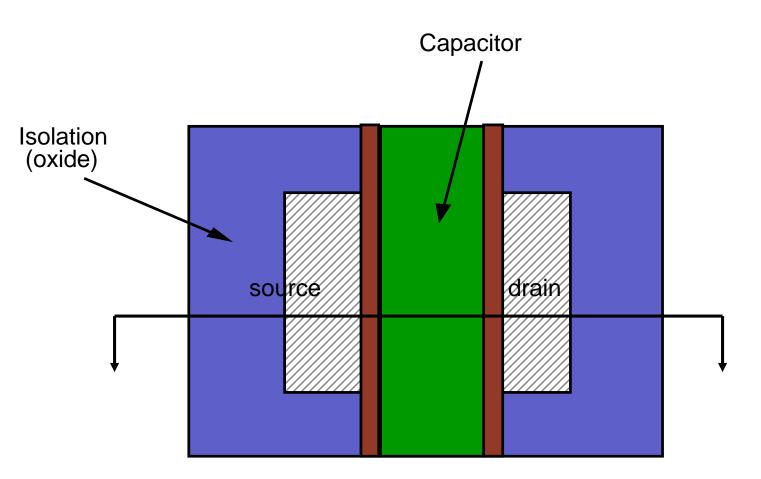
Anatomy of a MOSFET: Cross-Section

- A MOS transistor is nothing more than a voltage-controlled switch.
- A MOS transistor is really just a capacitor with two extra terminals.



Cross-Section View

Anatomy of a MOSFET: Top View



Top View



Semiconductor Device Types

- Analog semiconductor devices deal in precise electric properties, most commonly voltages. Transistors within the device are designed to measure and manipulate these properties. Analog devices are well suited to processing real-world signals, as electronic patterns are used to directly represent the original.
- Digital devices do not deal in the values of actual voltages; rather, they simply
 detect the presence or absence of a voltage. The presence of a voltage is
 represented digitally as a "1," with the absence represented as a "0." These 1s and
 Os can be processed and manipulated digitally with great flexibility.
- Mixed Signal These devices include both analog and digital circuitry. Mixed signal devices are difficult to design and build, but bring the benefits of both analog and digital processing together.



Device Types: Semiconductor Industry Association (SIA) Framework

- Discretes, Optoelectronics, Sensors Includes all non-integrated circuit semiconductor devices. A discrete is a single transistor in a package. Sensors are discrete devices that measure real-world input. Optoelectronics are discrete devices that produce or measure light.
- Analog Devices used to process real-world signals using electronic voltage patterns that represent the original. Includes SLICs (standard linear components) and ASSPs (applicationspecific analog ICs).
- Logic All non-microcomponent digital logic. Includes ASICs (custom logic), ASSPs (standard specialty logic products), FPGAs (programmable logic), display drivers and general purpose logic.
- Memory Memory devices are used to store data either for short periods of time or permanently.
 Includes volatile (DRAM, SRAM) and non-volatile (flash, ROM) memory.
- Microcomponents All digital processors, including microprocessors (MPUs), microcontrollers (MCUs) and digital signal processors (DSPs).

Microcomponents in Detail

Microcomponents:

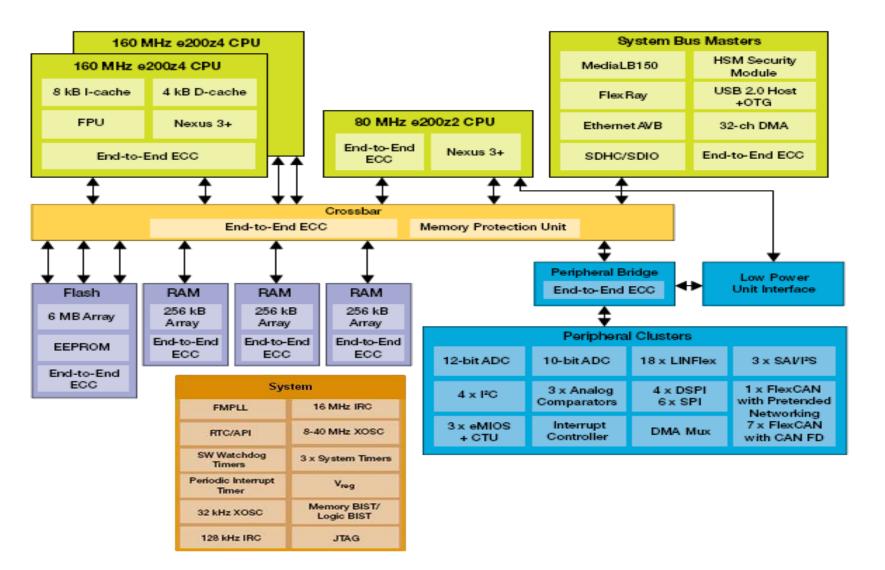
Devices designed to perform intensive compute processing and system control

Three Key Types:

- Microprocessors digital processors that execute instructions and perform system control functions. MPUs are optimized for general purpose data processing.
- Microcontrollers stand-alone devices that perform embedded compute functions within an overall system. MCUs contain single or multiple processing elements as well as on-chip, RAM, ROM, and I/O logic.
- Digital Signal Processors specialized high speed programmable processors designed to perform real-time processing of digital signals



Example Microcontroller – MPC5748G



PUBLIC 11

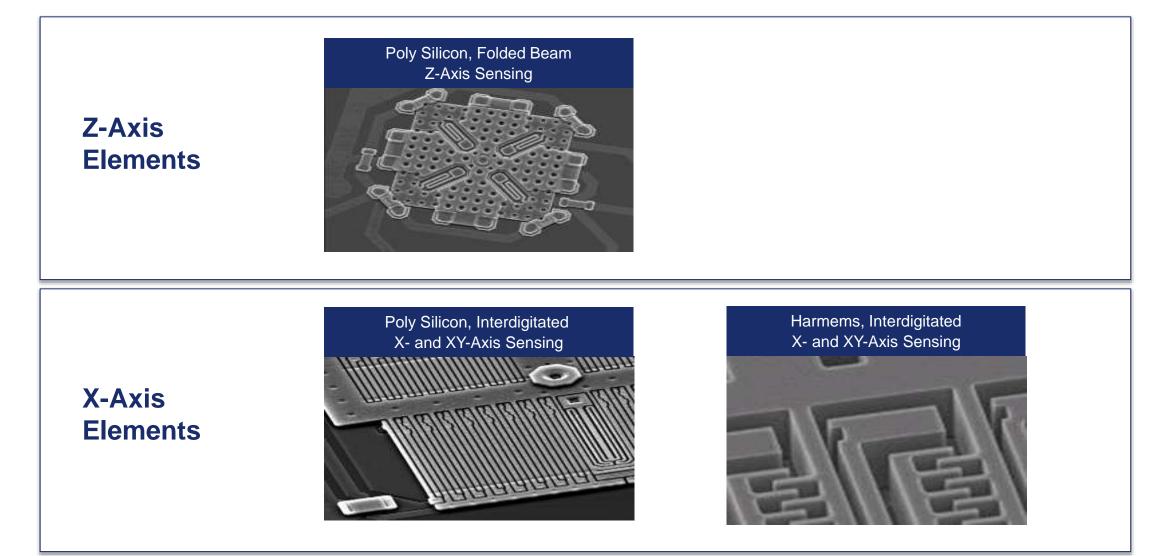


Packaging Options for Mixed-Signal Functions

Semi-Discrete Solution	Multi-die SiP	Monolithic SiP
Standard MCU	Single package	MCU and Analog on the same die
	Die-to-die bonding	
Application Specific Analog IC	Tangan and a start and a start and a start a st	Alternative walking
(ASIC)		



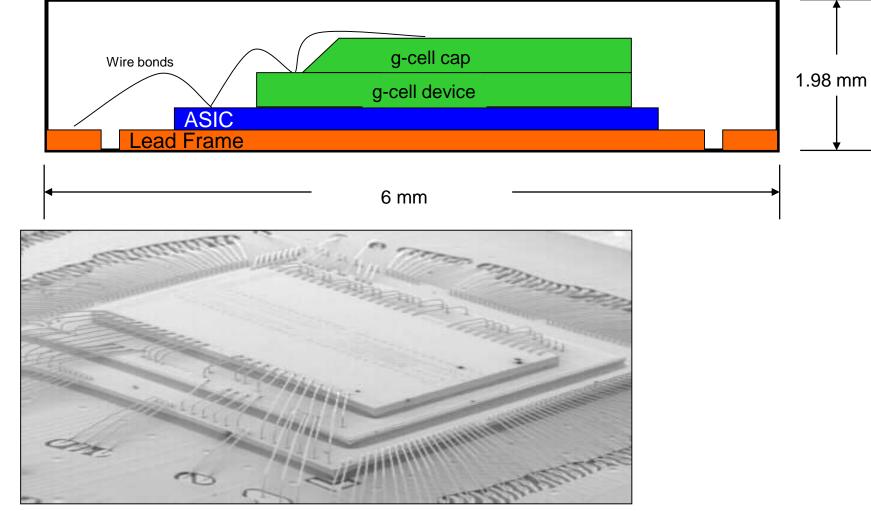
Example of Inertial Sensing Elements





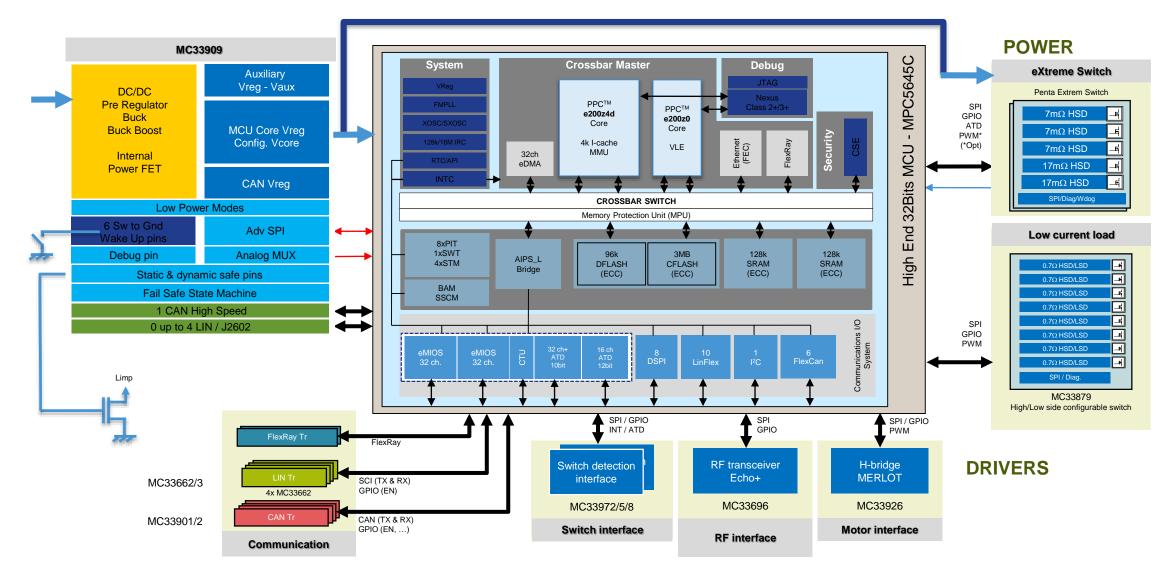
Stacked-Die Packaging for Sensors and Processors



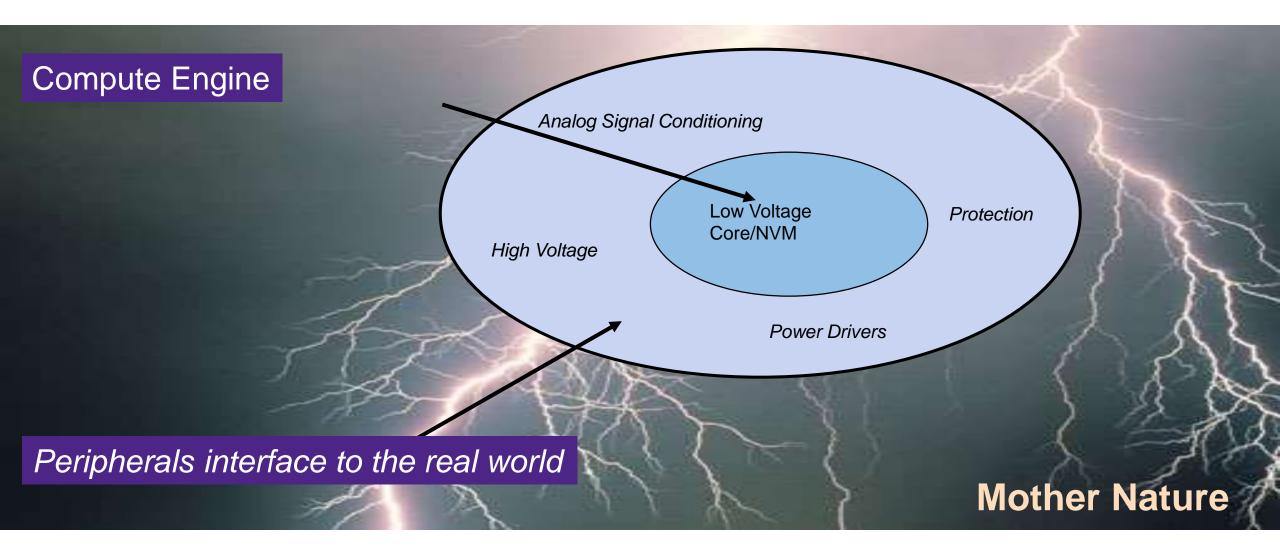




Body Controller Partitioning Example

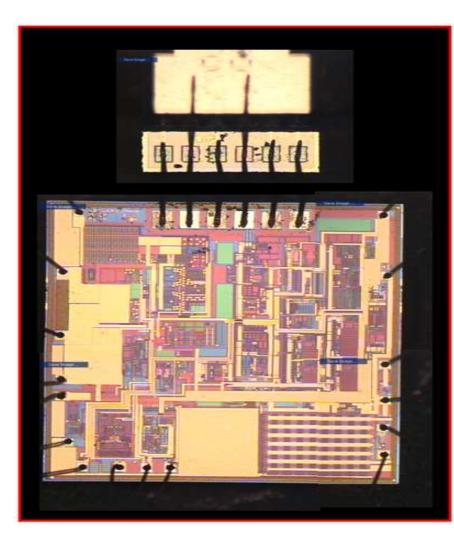


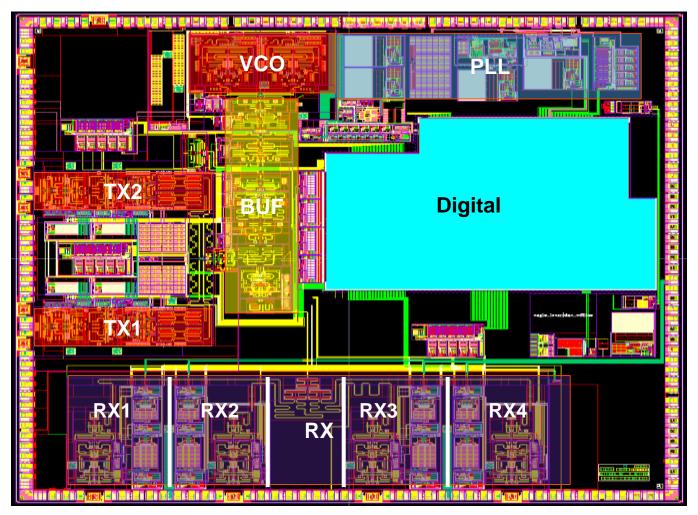
Control Modules – Functional Breakdown





Example Die Pictures of Integrated Circuits

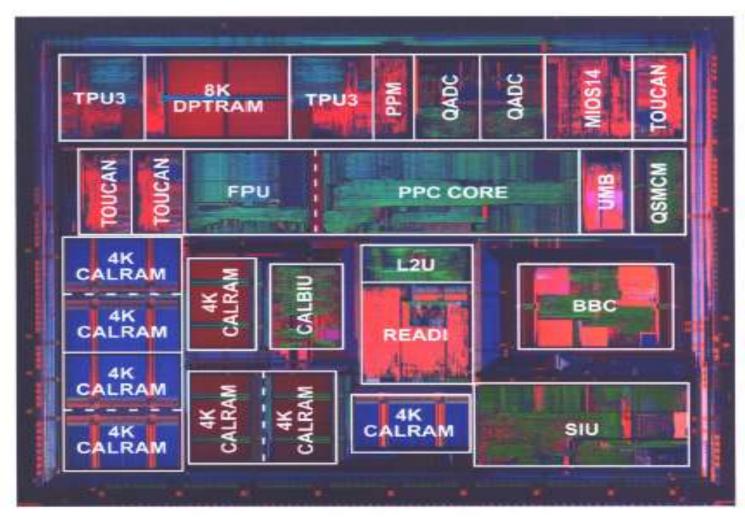




Radar Transceiver



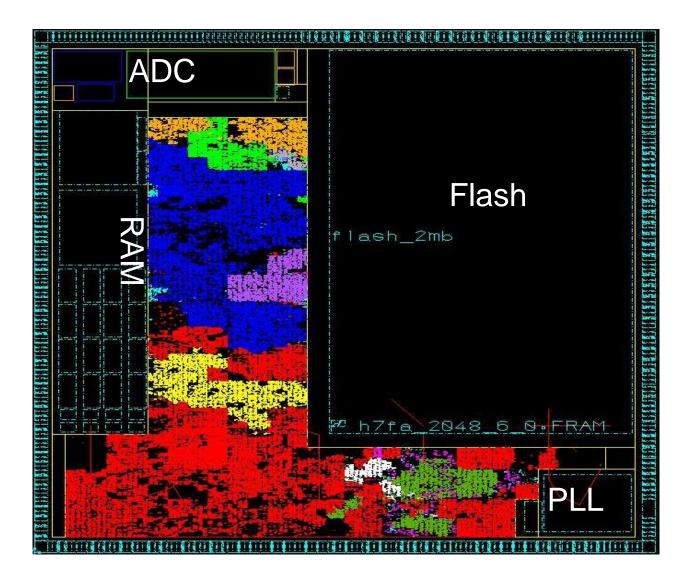
MPC561 Die Photo



- 32-bit MCU with Power Architecture[®] CPU core
- Die size = .55 cm2
- 5 million transistors
- 16 million vias and local interconnects
- 2 polysilicon layers
- 3 aluminum metal layers
- 0.25 µm technology



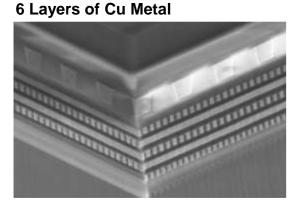
MPC5554 Floor Plan



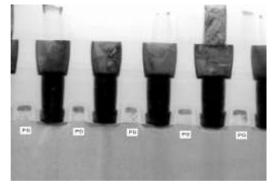
- Red CPU
- Blue eTPU
- Green eQADC
- Purple DSPI
- Yellow eMIOS
- Orange FlexCAN
- White EBI
- Dark Green SIU
- Magenta JTAG
- Grey SCI

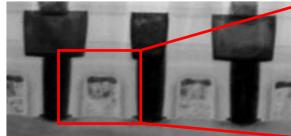
MPC5674F Technology Highlights

- ~350 process steps, 55 mask layers
- ~75 million transistors
- ~400 chips per 200 mm wafer
- Embedded ADC, SRAM, non-volatile memory



1.15 um² SRAM Bitcell Array





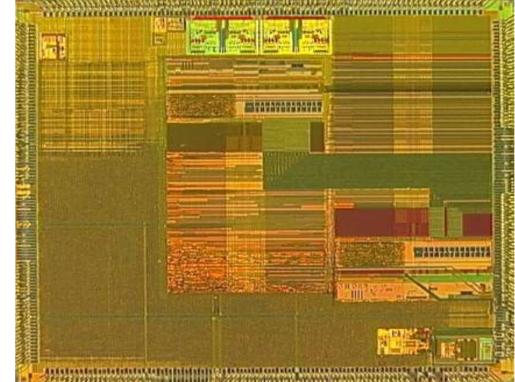
NVM Bitcell Array



NVM Bitcell



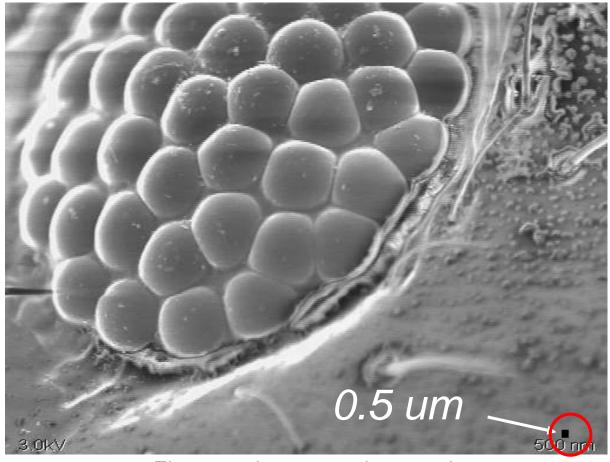




State-of-the-art Power Architecture® 32-bit MCU engine control 600+ DMIPS – MPC5674F



What is a Micron Between Friends?



Electron microscope photograph of a common Texas fire-ant eye

 0.5 micron is 1/200th the width of a human hair

1997 mainstream process

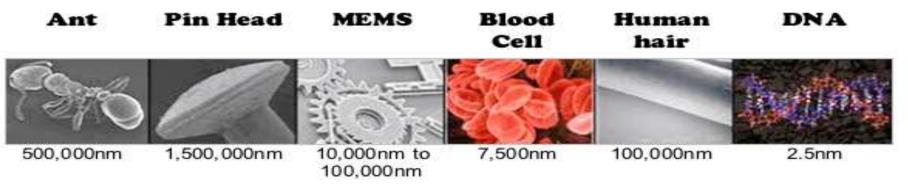
55 nm is 1/2000th the width of a human hair

2014 mainstream process



What is a Nanometer Between Friends?

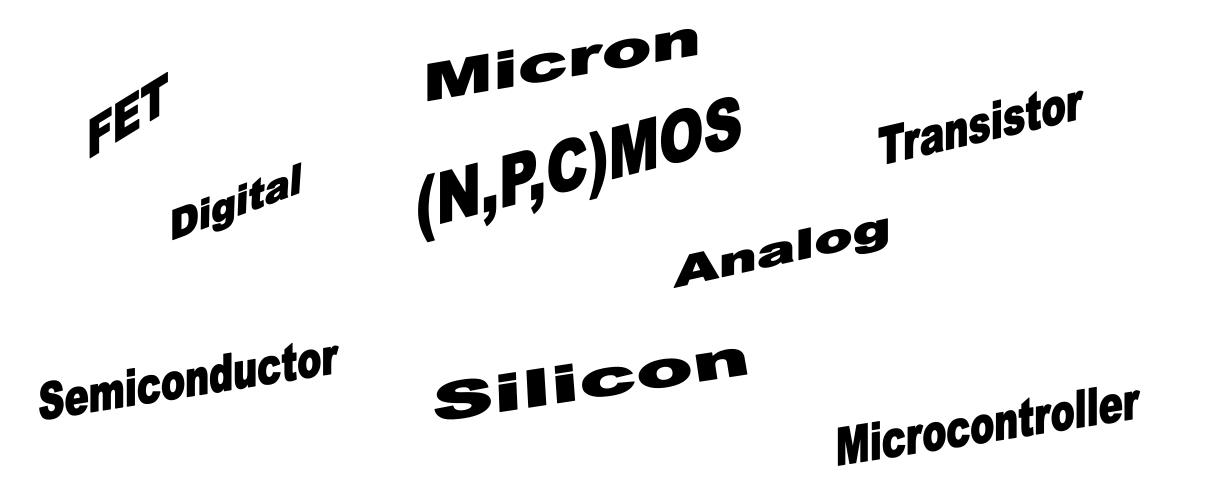




Source: nano.gov/nanotech-101/what/nano-size & http://www.nanosciencekits.org/



Semiconductor Terms and Acronyms: Review

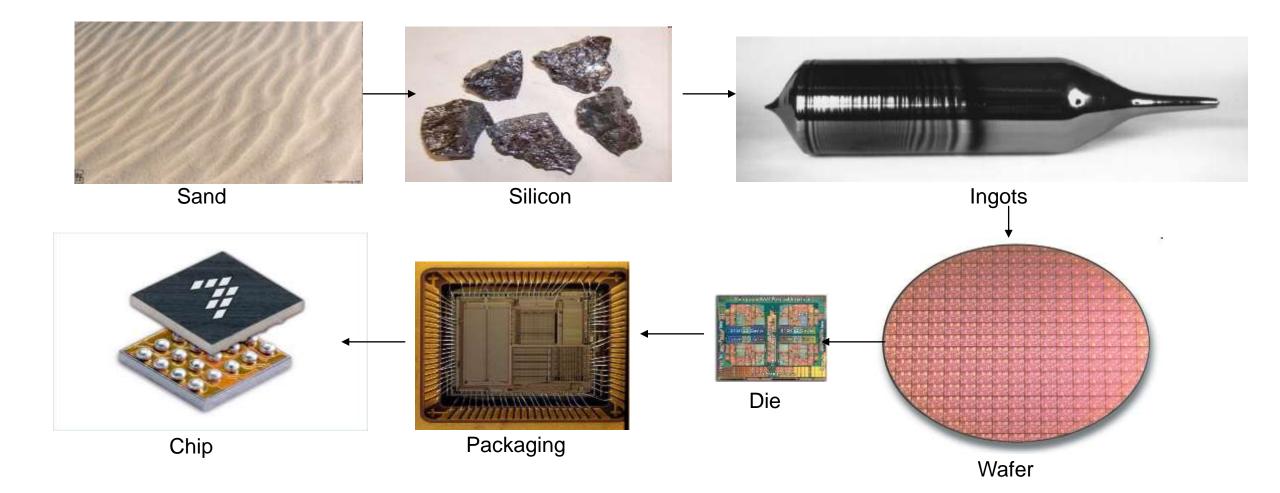




INTEGRATED CIRCUIT MANUFACTURING PROCESS



Semiconductor Manufacturing Overview



Semiconductor Overview: Fundamental Processes

CON YUNGI HALL

IC manufacturing uses a recursive deposition and masking process to define patterns of doped areas, isolation films and metal conductors to create solid state devices.

Raw silicon substrate

Photo spins on photoresist, aligns reticle and exposes wafer with reticle pattern. Develop removes resist from exposed areas.

Etch removes film layer that was uncovered during develop. Strips resist.

Implant dopants are implanted for electrical characteristics.

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Metals/Films

connects devices electrically and isolates circuit pathways.

CMP polishing technique to keep surfaces flat so more layers can be added

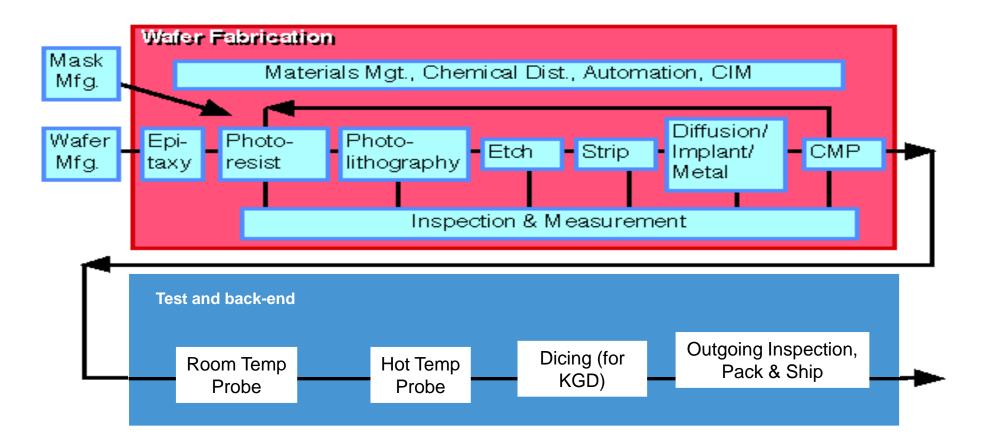
Substrate

Diffusion grows or deposits a layer of oxide, nitride, poly or similar material.

Probe/Test test device functions

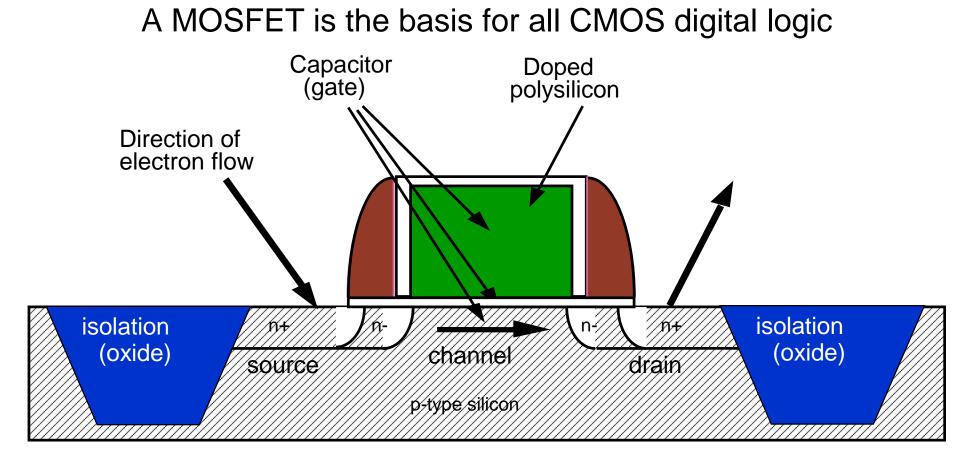


Semiconductor Front-End Manufacturing Process





Anatomy of a MOSFET: Cross-Section



Cross-Section View



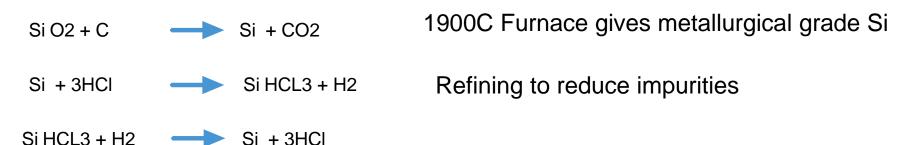
Preparing Silicon for Use in Integrated Circuits





 Silicon is the second most abundant element on earth after oxygen (25% of crust)

Purification operations

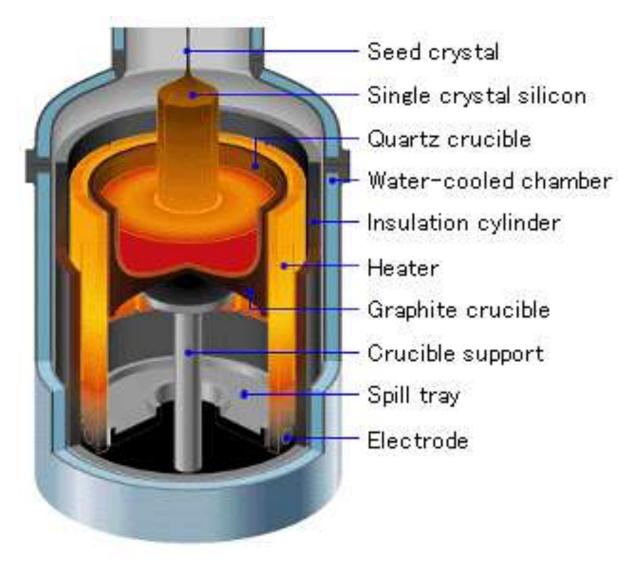


The white sand of Abel Tasman's beaches in New Zealand's South Island is a typical source of silicon dioxide.





Making an Ingot





- A pure silicon seed crystal is placed into a molten sand bath.
- This crystal will be pulled out slowly as it is rotated (1 mm per hour).
- The result is a pure silicon cylinder that is called an *ingot*.



Examples of a Completed Ingot



Single crystal silicon ingot length: 110 cm



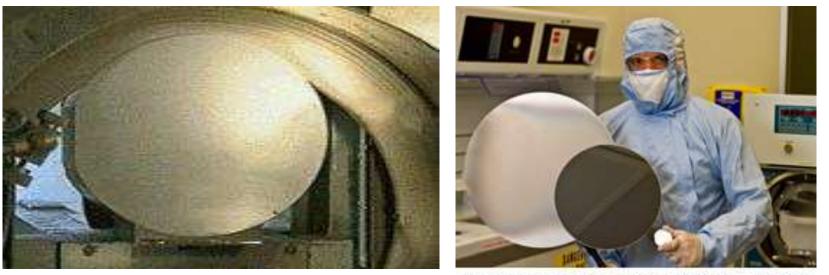
200mm Silicon Ingot





Preparing the Wafers

- The ingot is ground into the correct diameter for the wafers
- Then, it is sliced into very thin wafers
- This is usually done with a diamond saw



Wafer transition from 50mm to 300mm to 450mm



Slicing : 640µ thick



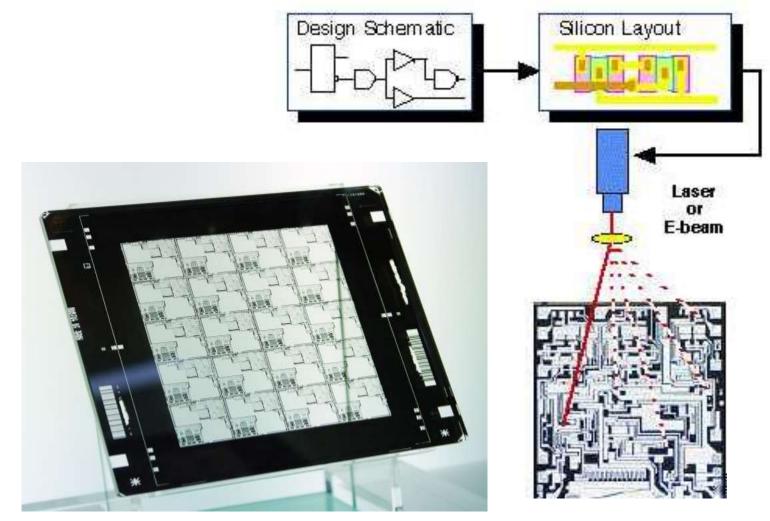
Mask-Making Process

The Process

- Start with ultra-pure glass plates with a surface deposition of chromium.
- Computer generated layouts of the IC drive a laser beam or electron beam to selectively remove chromium and create the mask or reticle.

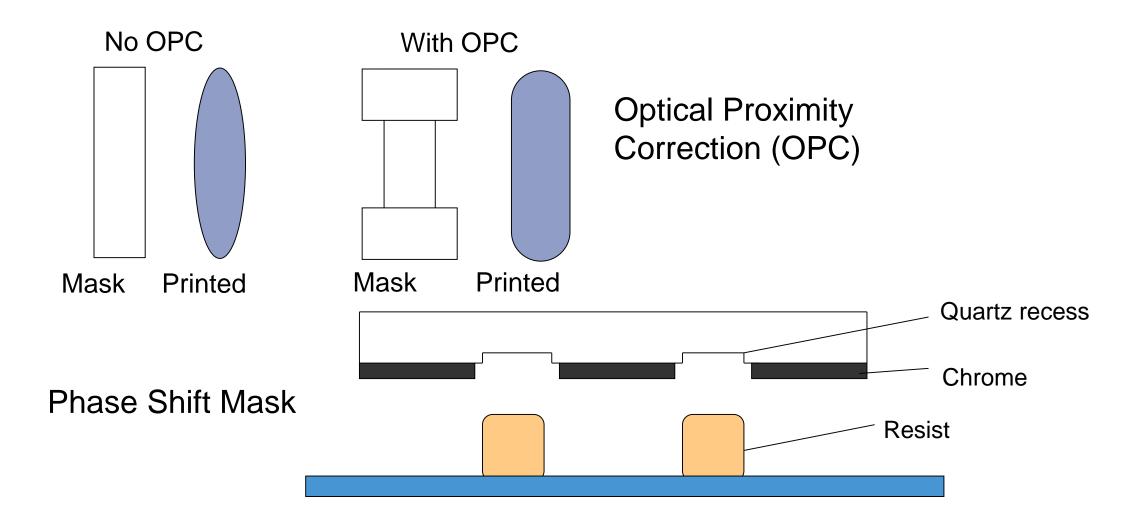
Design Driven

- Increased complexity
- Long write times



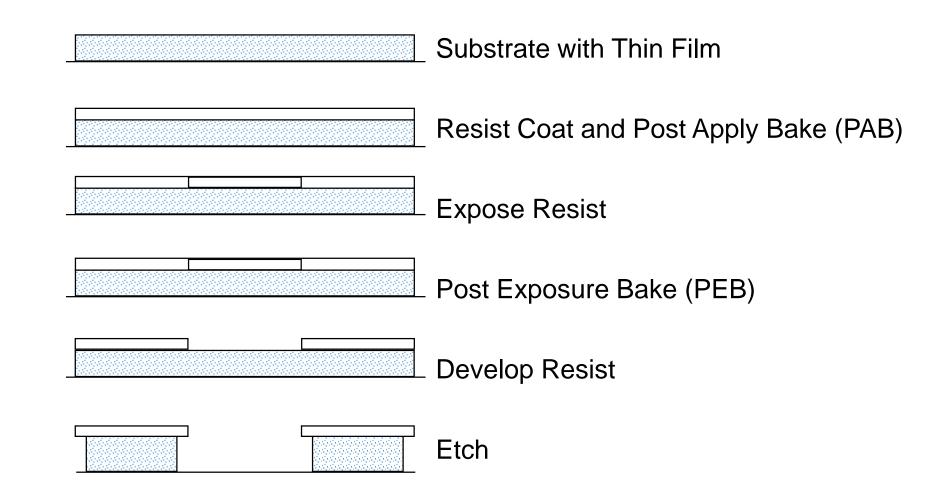


Small Geometries: Stretching the Wavelength



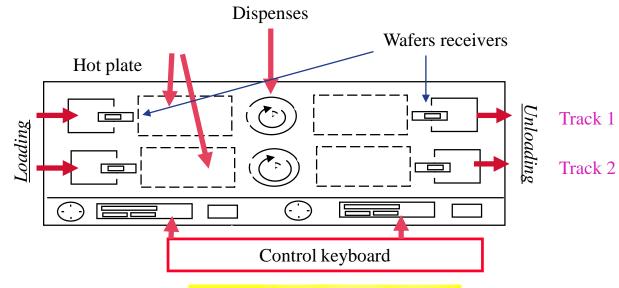


Lithography Process Overview

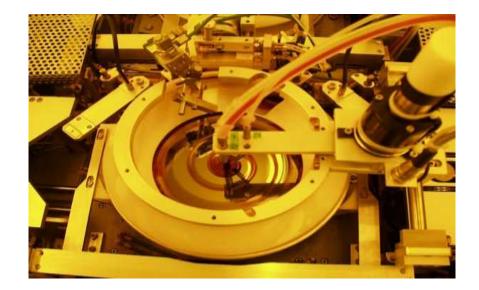


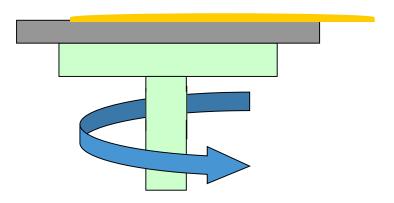


Adding Photoresist







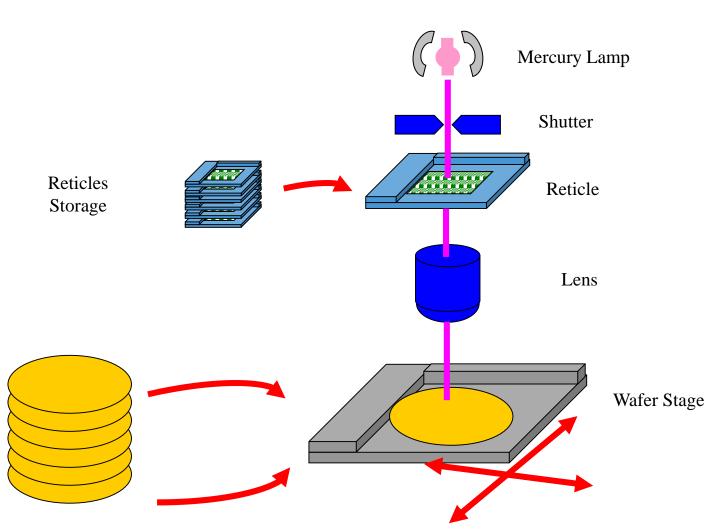






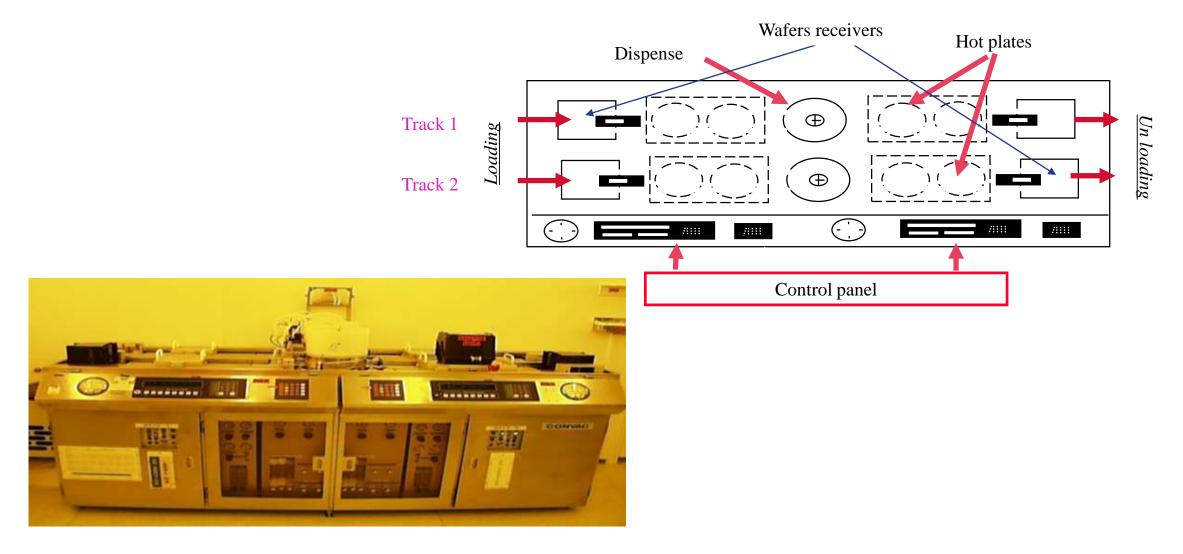


Wafer Loading /Unloading



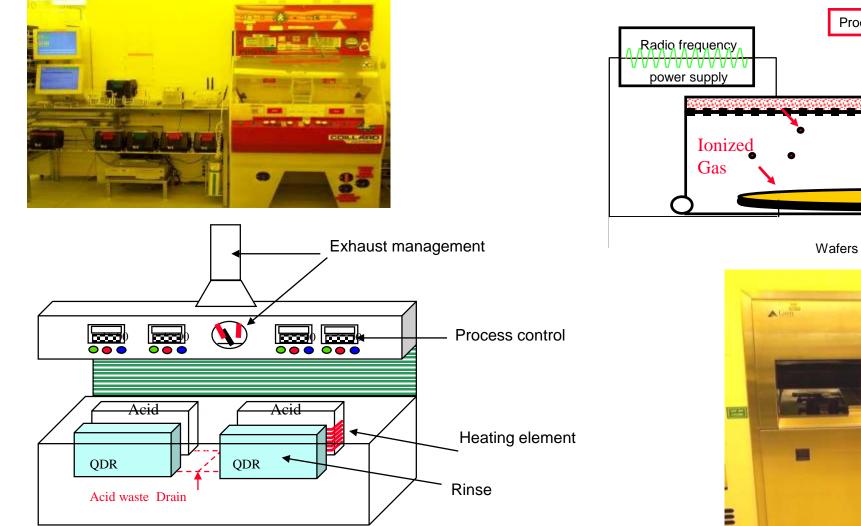


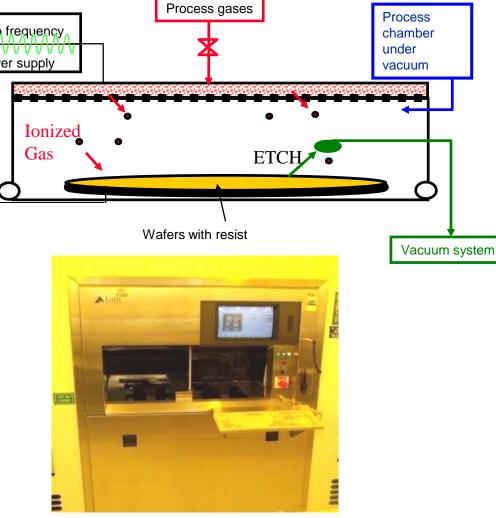
Develop





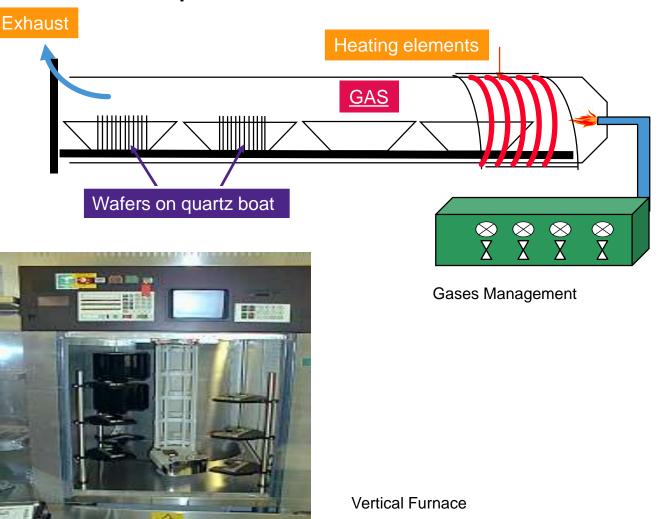
Etching (Chemical and Reactive Ion)





Diffusion Furnace

- Diffusion furnaces are classified as either horizontal or vertical.
- Vertical gives better process control and tends to be cleaner but takes up more space.
- Changing the process gases allow us to grow films (oxide, nitride, poly) or dope the wafers to change the electrical characteristics.
- They operate at temperatures generally between 650°C and 1200°C.
- Temperatures in furnaces are controlled to better than +/- 1°C.
- Furnaces can process 50-200 wafers per run depending on type of process.
- Process times can vary from 4-20 hours (thicker films take longer to grow/deposit).

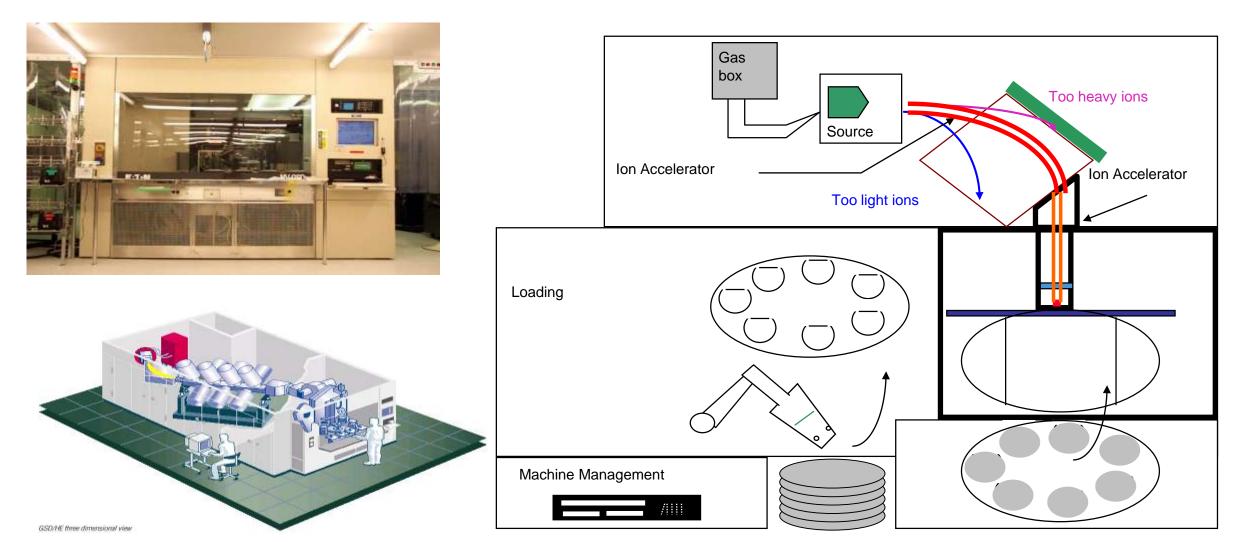


Atmospheric Pressure Furnace

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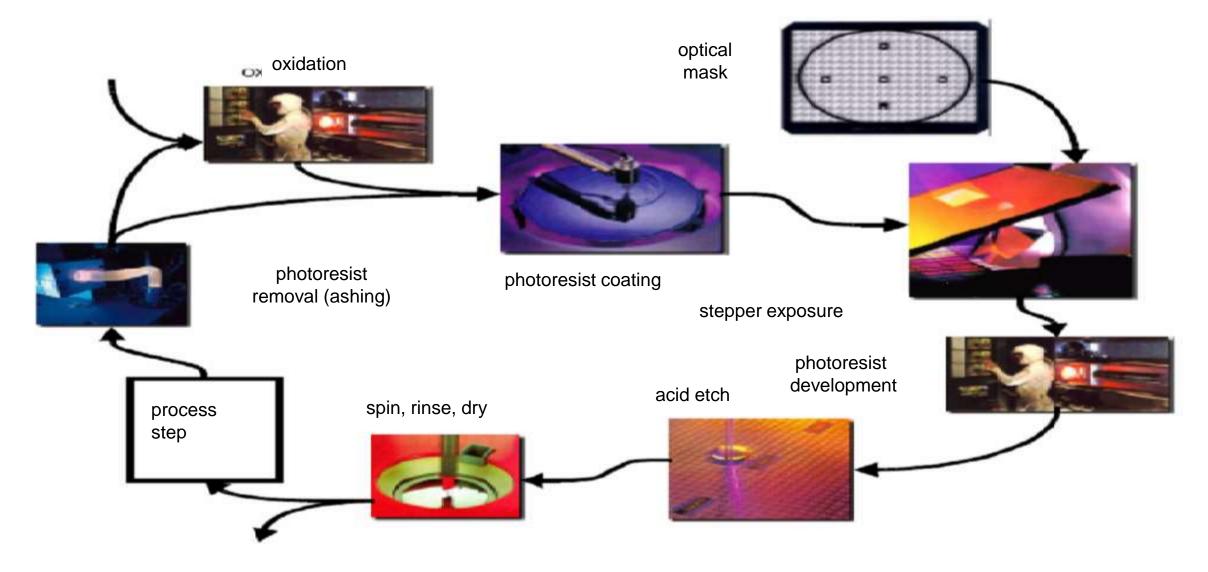


Ion Implantation and Annealing



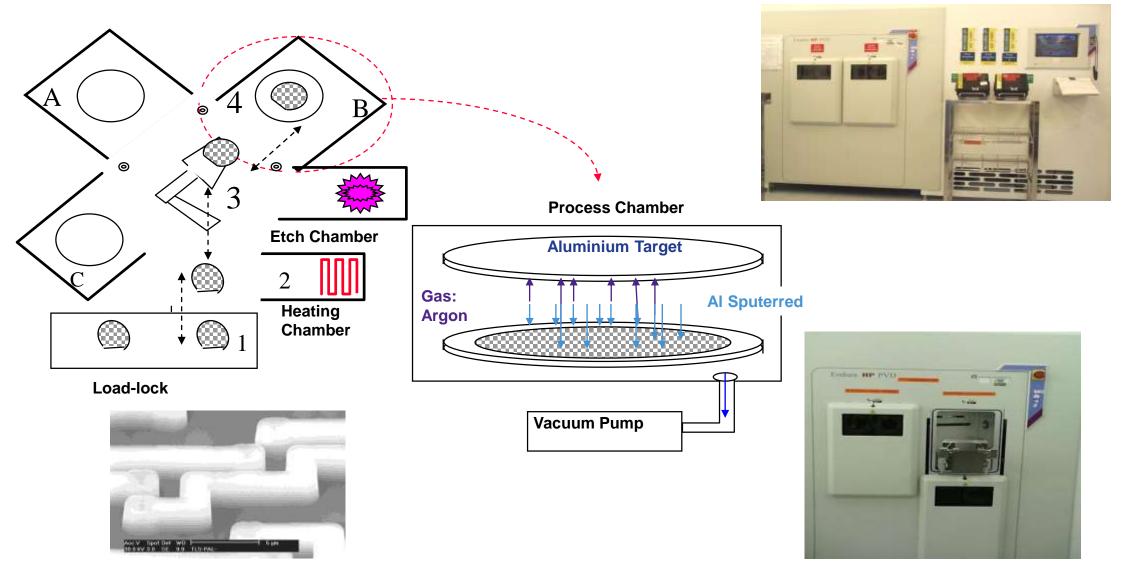


Typical Photo-Lithography Process



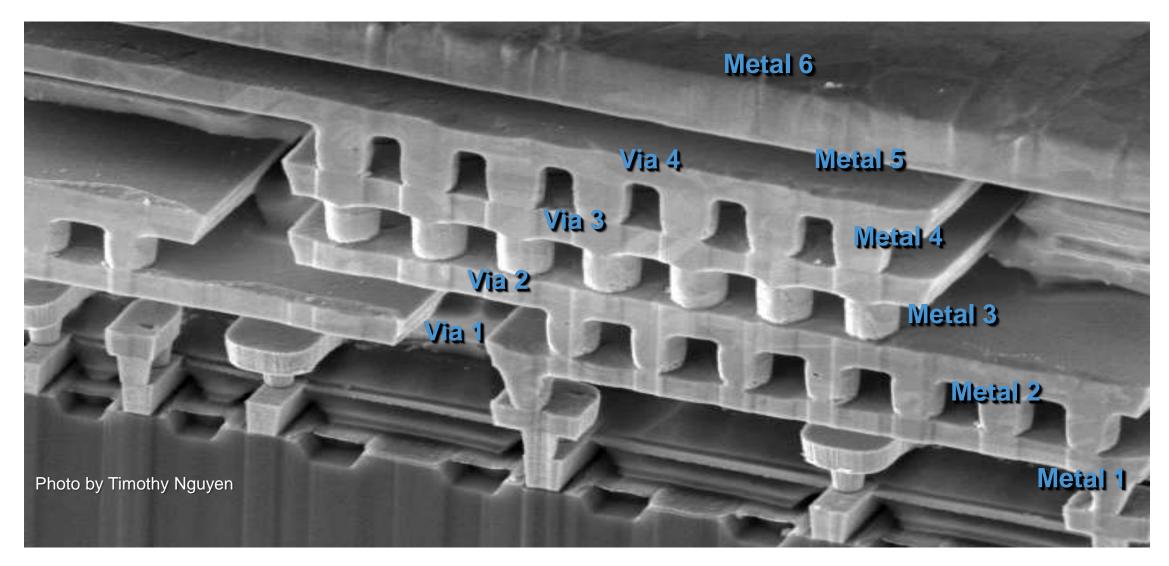


Metal Deposition





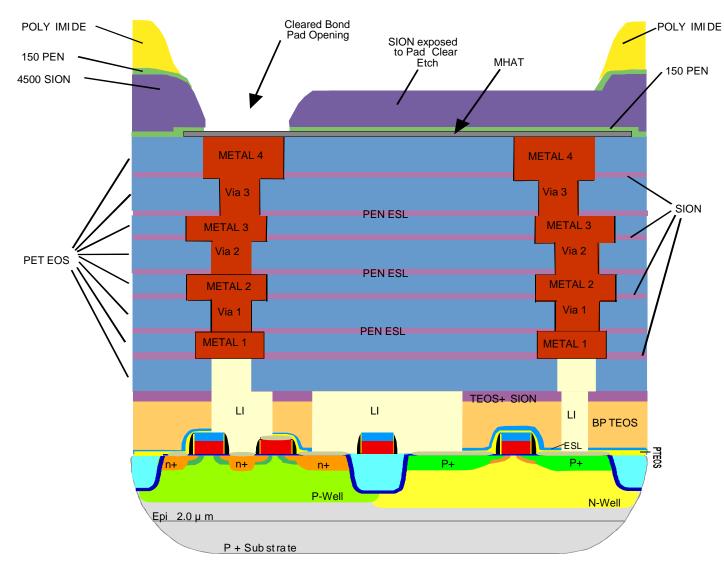
Copper Metallization







Typical Processor Cross-Section

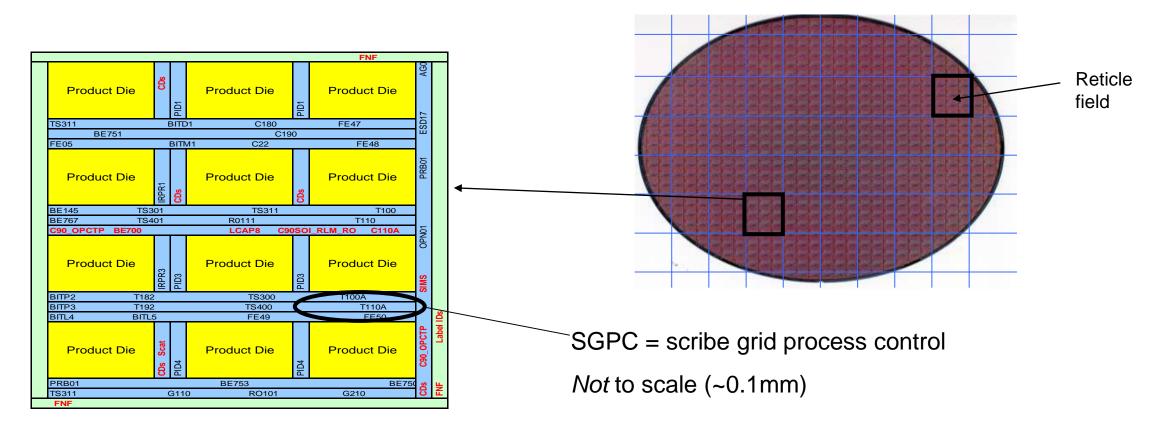


This process requires more than 190 stages. Each stage contains multiple sub-steps.



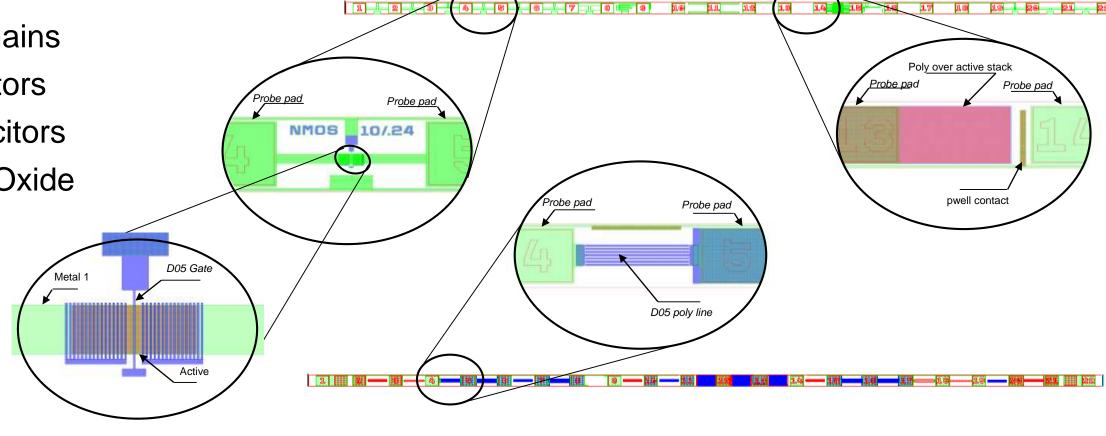
Class Probe

- Parametric testing of test structures
- Test structures in scribe lines between product die



Typical Class Probe Structures

- Transistors
- Metal to metal linkage
- Contact chains
- Via chains
- Resistors
- Capacitors
- Gate Oxide

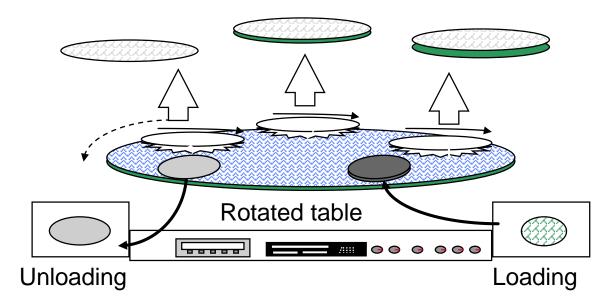




Backgrind



Wafer thickness is reduced from 640 μ



100 um thickness wafers Can be bent like paper

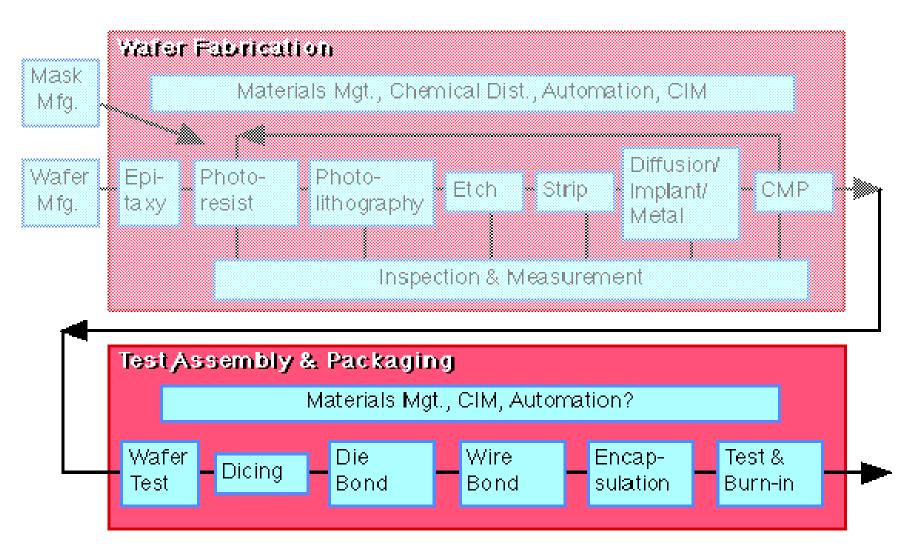




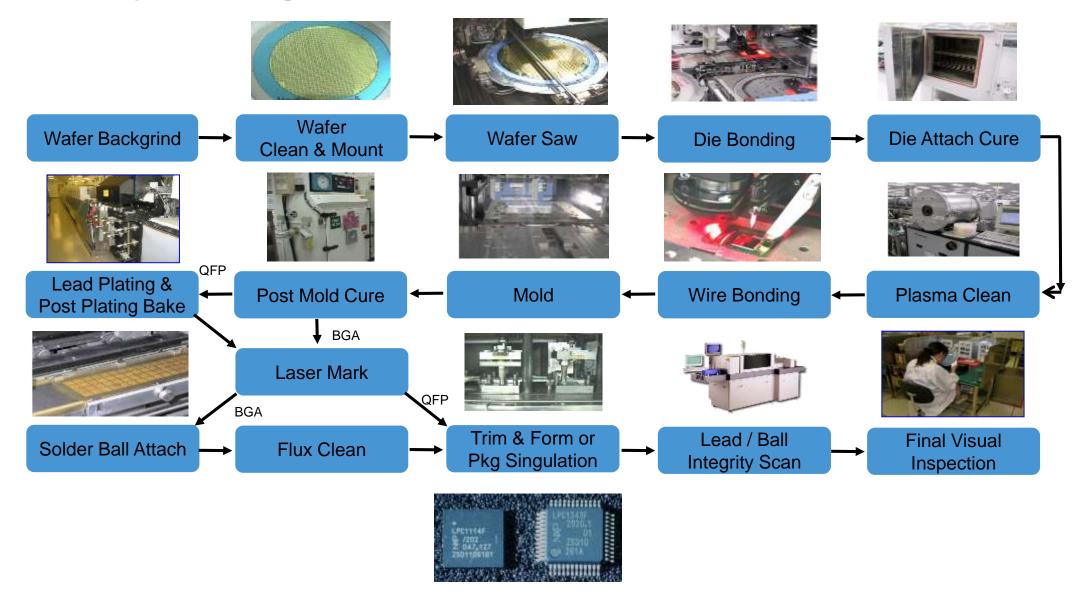
5 um thickness wafer



Test and Assembly Process

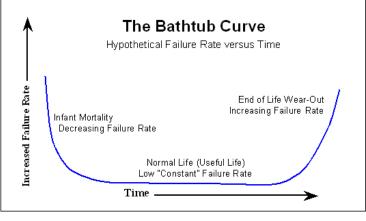


Assembly Package Process Flow



Burn-In





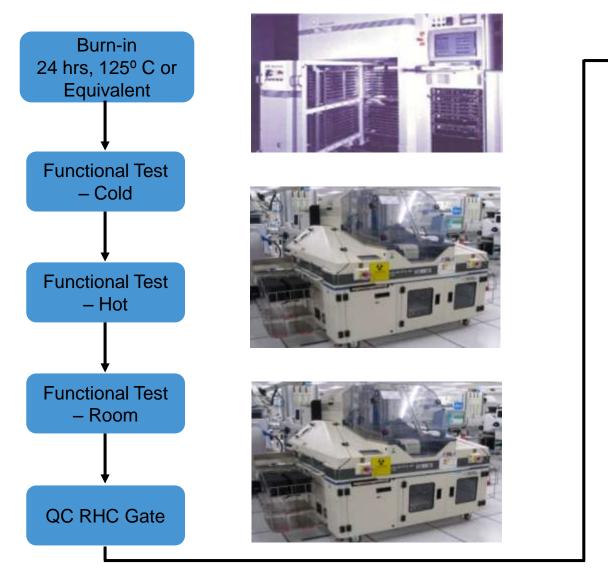


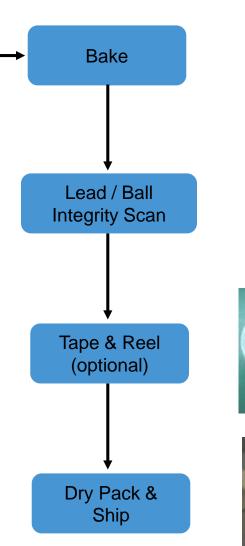






Final Test Process Flow











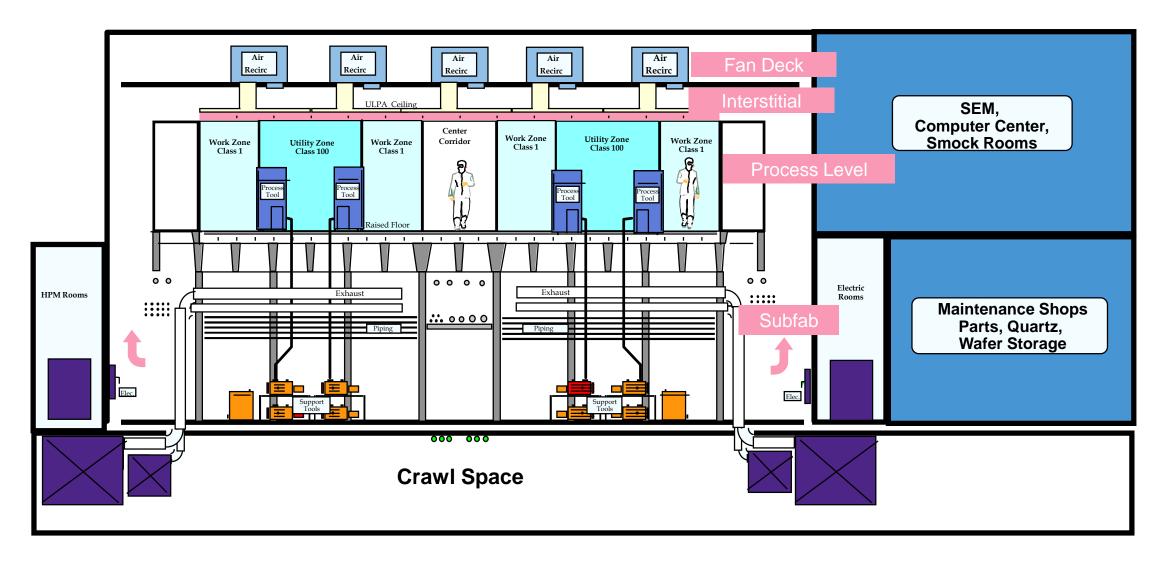




TOOLING, EQUIPMENT, AND INVESTMENT NEEDS FOR IC DESIGN AND MANUFACTURE



NXP ATMC Factory Configuration



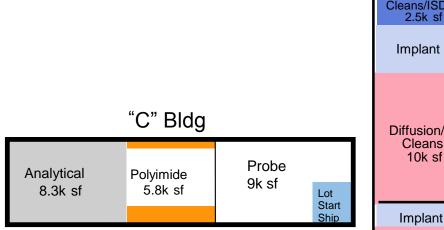


ATMC Cleanroom Airflow Filtration

- First stage makeup air pre-filters are 30% efficient for 3-10 um sized particles
- Second stage makeup air pre-filters (inside makeup air units) are 95% efficient for 0.3-1 µm sized particles
- Final stage filters (cleanroom ceiling grid) are Ultra Low Penetrating Air (ULPA) filters that are 99.9995% efficient for 0.1 um sized particles
- 100% cleanroom ceiling ULPA filter coverage in work zone (40% coverage in utility zone)
- Average laminar airflow velocity is 90-110 ft/min
- Cleanroom Airborne Particle Monitoring
 - Portable laser sensors are used to measure airborne particles at 561 locations throughout the cleanroom
 - Cleanroom Classification criteria specifies a maximum of 35 particles/ft3 (0.1 um) to achieve Class
 1 designation ATMC averages < 1 particle/ft3



NXP Chandler Fab Macro Layout



NUTIT & SUUIT						
Cleans/ISD 2.5k sf	CVD (TEOS,					
Implant	`PAS) 5.6k sf					
	Etch 4.2k sf					
Diffusion/ Cleans 10k sf	Photo i - line 7k sf					
Implant	YE 2.5k sf					
Diffusion/ Cleans 6.6k sf	Photo DUV					
Implant Cleans	6.1k sf					
CVD 4k sf	ETCH 8.2k sf					
ETCH CLNS	0.2K 51					
Metals (W,RTP)						

North & South

East Module (Bldg "M") Metals PVD 11 k sf MPD 11 k sf MRAM Copper 3.5 k sf MRAM CMP 22k sf

"A" Building to the East of "M" Building has additional 8k sqft of Probe



Ν

Oak Hill Texas Fab Facts

- 85,000+ square feet of sub-class 1 clean room space supporting wafer capacity of 6,000 WPW
- Factory operates 24 hours per day, 364 days per year
- Factory moves ~6,400,000 CFM, enough to fill 120 hot air balloons every minute
- 9,300 tons of refrigeration capacity, sufficient to cool 2,800 homes
- Factory uses 44,000,000 gallons of water/month, equivalent to 4,400 homes
- Factory uses ~215,000,000 KWH per year, equivalent to 6,000 homes
- Factory has more than 17 miles of stainless steel piping and more than 50 miles of electrical wiring



Typical Equipment Costs

200MM Equipment List for .18 Micron Facility

Equipment	Number	Price (\$M	Total (\$M)
Chemical Vapor Deposition	24	3	60
Physical Vapor Deposition	23	4	81
Steppers	54	8	432
Photoresist Processing	54	2	108
Etch	55	3	187
Cleaning- Strip	30	1	18
СМР	20	1	24
Diffusion - RTP	32	1	32
Ion Implant	13	3	43
Process Control	-	-	60
Automation/Handling	-	-	15
Miscellaneous	-	-	67
		Total	1,126

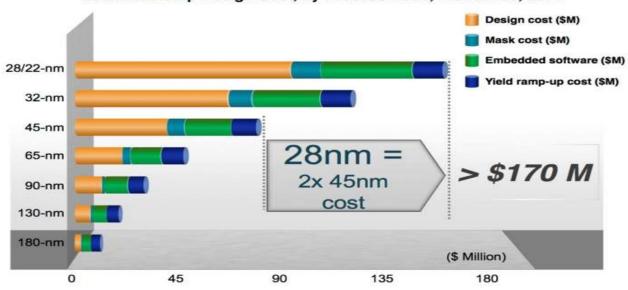
A new Stepper costs ~ \$80M and the total equipment cost is ~\$12B



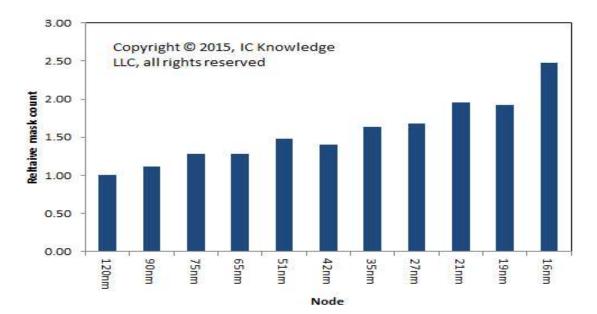
BUSINESS ASPECTS OF SEMICONDUCTOR FABRICATION



Staggering IC Design and Tooling Costs



Estimated Chip Design Cost, by Process Node, Worldwide, 2011



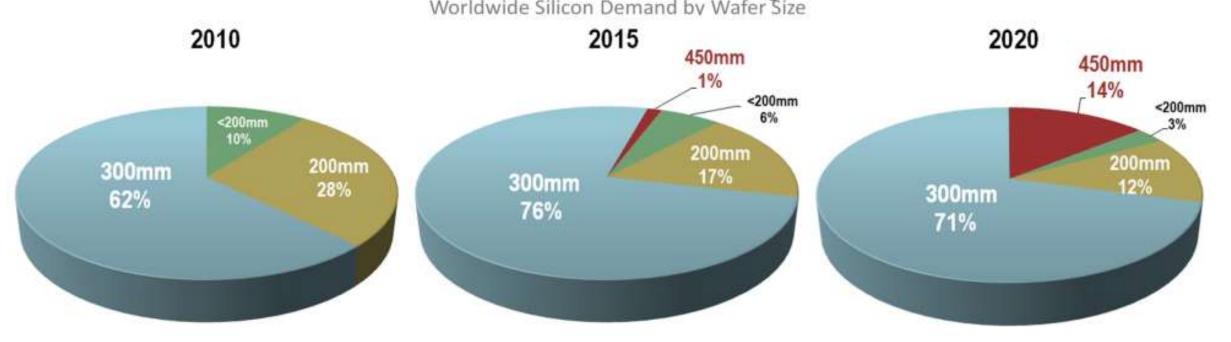
Source: IBS



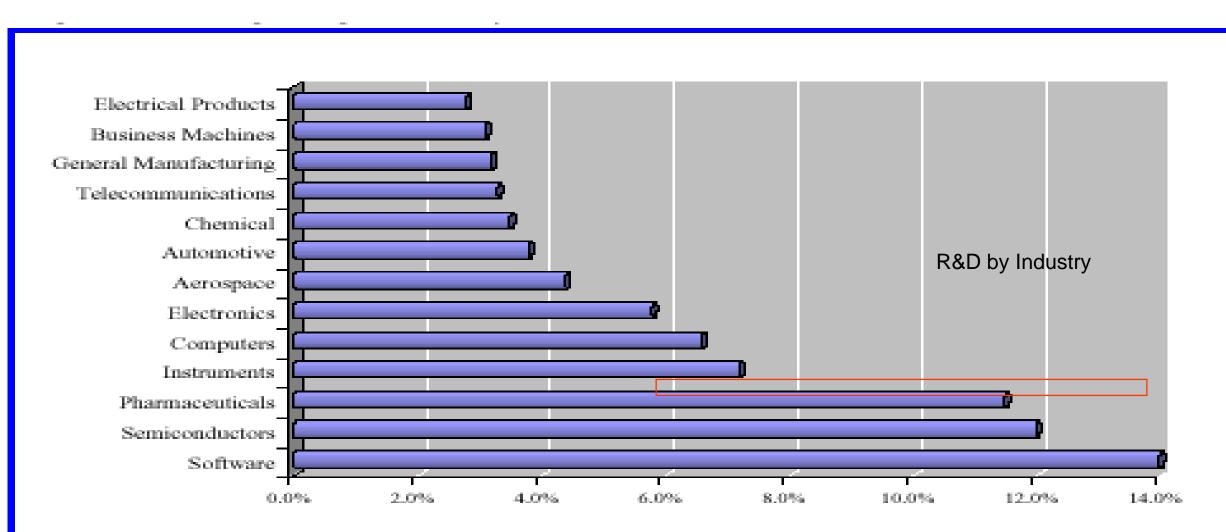
Wafer Size

Increased wafer size brings volume efficiencies.

Silicon Demand Trends by Wafer Size Worldwide Silicon Demand by Wafer Size



Research and Development



PERCENT OF SALES

Research and Development (2)

R&D Spending as a % of Sales

Top Semiconductor R&D Spenders (Companies with ≥\$1B in Spending)

12100000	2014 Rank	Company	Region		FOUNDRY	2014			2015			2015/2014
				MOI		Semi Sales (\$M)	R&D Exp (\$M)	R&D/Sales (%)	Semi Sales (\$M)	R&D Exp (\$M)	R&D/Sales (%)	
1	1	Intel	Americas	•		51,400	11,537	22.4%	50,494	12,128	24.0%	5%
2	2	Qualcomm	Americas		•	19,291	3,695	19.2%	16,032	3,702	23.1%	0%
3	3	Samsung	Asia-Pac	•		37,810	2,965	7.8%	41,606	3,125	7.5%	5%
4	4	Broadcom	Americas		•	8,428	2,373	28.2%	8,421	2,105	25.0%	-11%
5	5	TSMC	Asia-Pac		•	24,975	1,874	7.5%	26,439	2,068	7.8%	10%
6	7	Micron	Americas	•		16,720	1,598	9.6%	14,816	1,695	11.4%	6%
7	6	Toshiba	Japan	•		11,040	1,853	16.8%	9,734	1,655	17.0%	-11%
8	9	MediaTek	Asia-Pac		•	7,032	1,430	20.3%	6,699	1,460	21.8%	2%
9	12	SK Hynix	Asia-Pac	•		16,286	1,340	8.2%	16,917	1,421	8.4%	6%
10	8	ST	Europe	•		7,384	1,520	20.6%	6,840	1,409	20.6%	-7%
		Top 10 Total			Ī	200,366	30,185	15.1%	197,998	30,768	15.5%	2%

Source: Company reports, IC Insights' Strategic Reviews database

Wafer Costs for Advanced Nodes

WAFER COST COMPARISON

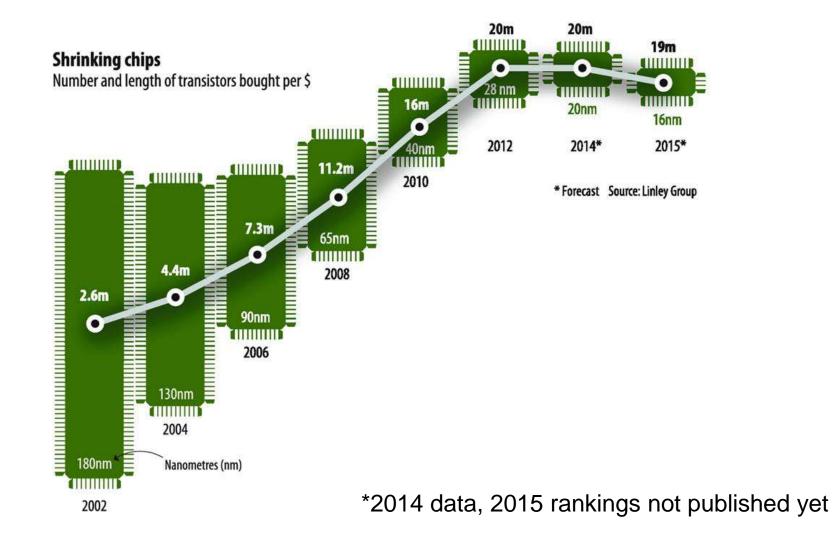
IBS

(\$)	Q4/2015	Q4/2016	Q4/2017
28nm bulk CMOS	2,428.90	1,786.34	1,601.75
28nm FD SOI	2, 4 01.35	1,825.46	1,645.37
20nm bulk CMOS	3,048.31	2,889.14	2,775.45
16/14nm FinFET	4 ,775.85	4,426.14	4,017.39
14nm FD SOI	3,598. <mark>4</mark> 2	3,369.36	3,099.87

Source: IBS



Financial Benefit of New Fabrication Processes is Slowing





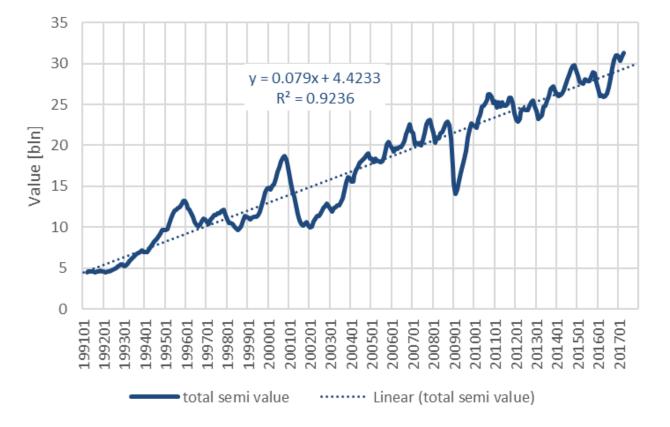
SEMICONDUCTOR MARKET DYNAMICS



SEMICONDUCTORS HAVE GROWN TO A \$335 BLN MARKET

• Semiconductor market is more volatile than overall market it is upstream in supply chain (Bull Whip Effect)

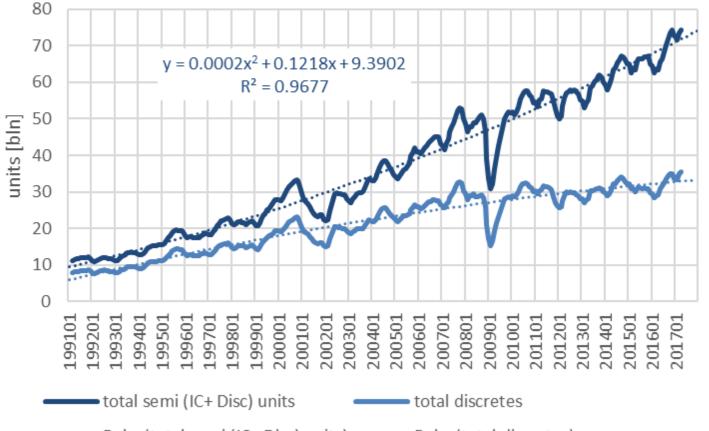
total monthly semi value





AND MONTHLY UNITS PRODUCTION HAS GROWTH 400% OVER LAST 20 YEARS

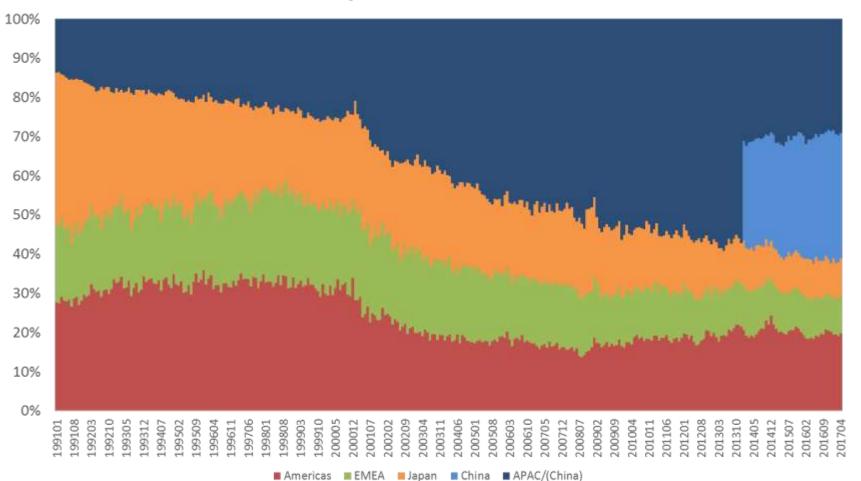
total monthly semi units



······ Poly. (total semi (IC+ Disc) units) ····· Poly. (total discretes)



Market has moved from mature economies to emerging countries

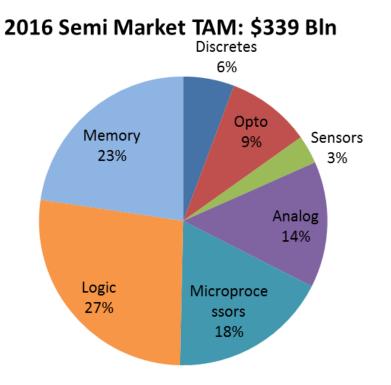


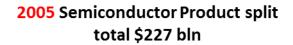
Regional Semi Market Shares

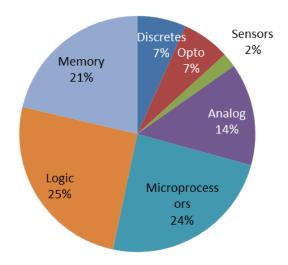


Memory and Logic have taken share from Microprocessors in the last decade

• Smartphones have been growth driver while PC market has been stable





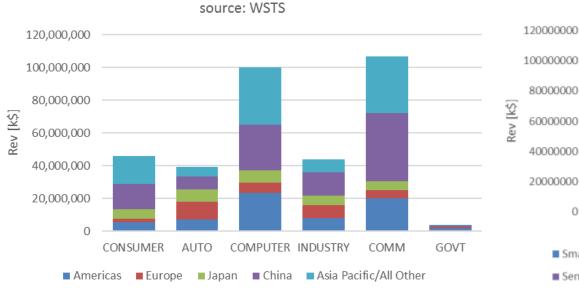


Communications market the largest end market

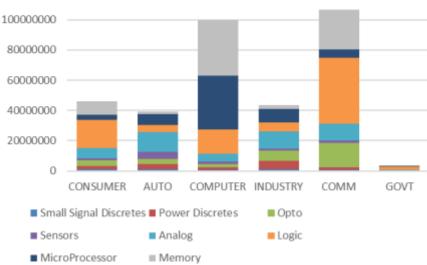
- With ~1.5 (smart)phones, the communications market is the leading end market in semiconductors. Maturing now
- Automotive and IoT considered to be future growth drivers

2016 End Markets by Shipping Region

- Automotive and Industrial market still much more analog oriented than Mass consumer market (PC, Smartphone, TV)





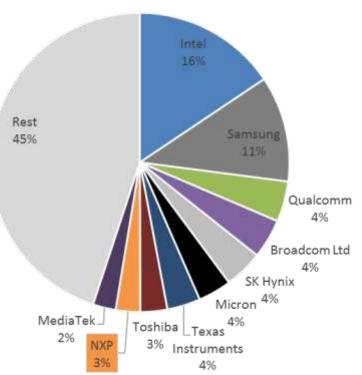




Market is consolidation. Continued strong M&A activity in 2016

 Memory companies (Samsung, Micron, Hynix) have grown together with a selective group of fabless SoC players (Broadcom, Qualcomm)





2016 Market Share



SEMICONDUCTOR MANUFACTURING VIDEO



QUESTIONS









SECURE CONNECTIONS FOR A SMARTER WORLD

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